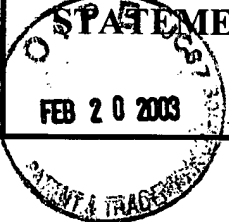


INFORMATION DISCLOSURE STATEMENT 	Atty. Docket No.: 110.01420101	Serial No.: 09/691,006
	Applicant(s): LEGER et al.	Confirmation No.: 4510
	Application Filing Date: October 18, 2000	Group: 2877
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U.S. PATENT DOCUMENTS


Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
1AP	5,133,601	07/28/92	Cohen et al.			
1AP	5,204,734	04/20/93	Cohen et al.			
1AP	5,359,622	10/25/94	Shih			
1AP	5,486,701	01/23/96	Norton et al.			
1AP	5,521,705	05/28/96	Oldenbourg et al.			
1AP	5,602,820	02/11/97	Wickramasinghe et al.			
1AP	5,754,296	05/19/98	Law			

FOREIGN PATENT DOCUMENTS

Examiner Initial	Document Number	Date	Country	Class	Subclass	Translation	
						Yes	No
			None				

OTHER DOCUMENTS (Including Authors, Title, Date, Pertinent Papers, etc.)

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1AP	Absolute Ellipsometry (AE). Therna-Wave Measurement Technologies [retrieved from the Internet on 2/11/2003]. http://thermawave.com/technology/ae.htm , 1 page.
1AP	Ashkin, "History of optical trapping and manipulation of small-neutral particle, atoms and molecules," <i>IEEE Journal on selected topics in Quantum Electronics</i> , 2000; 6:841-856.
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17P	Zhan et al., "Interferometric measurement of the geometric phase in space-variant polarization manipulations," <i>Optics Communications</i> , 2002; 213:241-245.
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